APPLICATION DATA SHEET

Electronic Version 0.0.11

Stylesheet Version: 1.0

Attorney Docket Number: 740756-2718

_ Publication Filing Type:

new-utility

Application Type:

utility

Title of Invention:

FILM FORMATION METHOD AND MANUFACTURING METHOD OF

SEMICONDUCTOR DEVICE

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Foreign Priority:

2003-076646

JP 2003-03-19

Priority Claimed

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